

Books and Parts of Books

- [1] S. Hong, G. May, S. Lee, and D. Park, "Modular Neural Networks for Semiconductor Manufacturing Process Modeling and Characterization: Application to Plasma Processing," *Intelligent Engineering Systems Through Artificial Neural Networks*, vol. 14, pp. 935-940, (C.H. Dagli, Ed.), New York: ASME Press, 2004.
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Conference Proceedings

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- [3] G. May, "SURE: Summer Undergraduate Research in Engineering/Science," *NSF Engineering and Computing Education Grantees Meeting*, Washington, DC, Feb., 2005.
- [4] S. Hong, G. May, A. Skumanich, and J. Yamartino, "Automated Fault Detection and Classification of Etch Systems Using Modular Neural Networks," *51st International American Vacuum Society Symposium*, Anaheim, CA, Nov., 2004.
- [5] G. May, "Building Collaborations between TWIs and HBCUs," **Invited Seminar**, *AGEM Winter Scholar Symposium*, Oxford, MS, Jan., 2004.
- [6] G. May, "Defining and Sustaining Quality Mentoring," **Invited Seminar**, *Richard Tapia Conference on Diversity in Computing*, Atlanta, GA, Oct., 2003.
- [7] G. May, "STEM Pathways: Graduate Education to the Professoriate," **Invited Seminar**, *NSF STEM Pathways Workshop*, Washington, DC, Oct., 2003.
- [8] G. May, "SURE: Summer Undergraduate Research in Engineering/Science," *NSF Engineering & Computing Education Grantee Meeting*, Washington, DC, September, 2003.
- [9] G. May, "Integrating Research and Education," **Invited Seminar**, *QEM Scholarly Technical Assistance Workshop for NASA FAR Recipients*, Atlanta, GA, Sept., 2003.
- [10] G. May, "A Comprehensive Approach to Nanosystems Education," **Invited Seminar**, *InterPACK 2003*, Maui, HI, July, 2003.
- [11] G. May, "Best Practices in Recruitment, Retention, and Promotion of Underrepresented Faculty in ECE," **Invited Seminar**, *NSF Agent of Change Workshop*, Arlington, VA, June, 2003.
- [12] G. Triplett, G. May, and A. Brown, "Interrelationships in the Electronic and Structural Characteristics of AlGaAsSb-InAs HEMT Structures," *45th Elec. Mat. Conf.*, Salt Lake City, UT, June, 2003.
- [13] A. Brown, M. Losurdo, G. Bruno, T. Brown, and G. May, "A Chemical and Kinetic Study of P-for-As Anion Exchange Reactions in GaAs/GaAsP Superlattice Structures," *45th Elec. Mat. Conf.*, Salt Lake City, UT, June, 2003.
- [14] G. Triplett, G. May, and A. Brown, "The Impact of the Inverted Interface (InAs-on-AlSb) on InAs/AlSb High Electron Mobility Transistor Structures Grown by Molecular Beam Epitaxy," *Workshop on Compound Semiconductor Materials & Devices*, Atlanta, GA, February, 2003.
- [15] M. Losurdo, G. Bruno, T. Brown, G. May, and A. Brown, "Anion Exchange Reactions and Isoelectric AsSb Formation: GaSbyAs1-y/GaAs and GaAsySb1-y/GaSb Superlattice Interface Quality," *44th Elec. Mat. Conf.*, Santa Barbara, CA, June, 2002.
- [16] T. Brown, G. May, A. Brown, M. Losurdo, M. Giangregorio, P. Capezzuto, and G. Bruno, "Characterization of Anion Exchange for Mixed Group V Heterostructures during Molecular Beam Epitaxy," *44th Elec. Mat. Conf.*, Santa Barbara, CA, June, 2002.
- [17] G. May, "Best Practices in Recruitment and Retention of Minorities in Science, Mathematics, and Engineering," **Invited Seminar**, *AAAS Annual Meeting*, San Francisco, CA, Feb., 2001.
- [18] G. May, "Best Practices in Recruiting and Retaining Minority Graduate Students," **Invited Seminar**, *Seventh Annual Institute on Teaching and Mentoring*, Orlando, FL, Oct., 2000.
- [19] G. May, "Intelligent Semiconductor Manufacturing Using AI and Neural Networks," **Invited Seminar**, University of California, Berkeley, CA, April, 2000.
- [20] G. May, "Diversity in Engineering," **Invited Seminar**, Purdue University, West Lafayette, IN, July, 1999.
- [21] G. May, "Intelligent Semiconductor Manufacturing Using AI and Neural Networks," **Invited Seminar**, Cornell

- University, Ithaca, NY, April, 1999.
- [22] G. May, "Georgia Tech's Model for Undergraduate Packaging Education," *2nd Internat'l Academic Conf. on Packaging Research and Education*, Atlanta, GA, March, 1999.
- [23] G. May, "Career Paths for PhD Recipients," Panel Discussion at *NSBE National Convention*, Kansas City, MO, March, 1999.
- [24] G. May, "The Minority Undergraduate Research Program at Georgia Tech," **Invited Seminar**, *NAMEPA National Conference*, Atlanta, GA, Feb., 1999.
- [25] G. May, "Evaluation the Undergraduate Research Program at Georgia Tech," **Invited Seminar**, *ASEE Annual Conf.*, Seattle, WA, June, 1998.
- [26] S. Ralph, B. Washburn, S. Prabhu, G. Dagnall, T. Kim, C. Yi, C., K. Lee, E. Roberts, T. Brown, G. May, R. Metzger, and A., Brown, "Ultrafast Carrier Lifetimes and Electronic Compensation in Low Temperature Grown Be-doped InGaAs," *40th Elec. Mat. Conf.*, Charlottesville, VA, June, 1998.
- [27] S. Ralph, G. Dagnall, E. Roberts, G. May, and A. Brown, "Analysis of Be-Doped LT InGaAs:Be," *40th Elec. Mat. Conf.*, Charlottesville, VA, June, 1998.
- [28] W. Doolittle, T. Kropenwicki, A. Taylor, S. Stock, P. Kohl, N. Jokerst, R. Metzger, S. Kang, K. Lee, G. May, and A. Brown, "Improvements in the Quality of AlGa_N, InGa_N, and GaN Grown on Lithium Gallate via Plasma Assisted Molecular Beam Epitaxy," *40th Elec. Mat. Conf.*, Charlottesville, VA, June, 1998.
- [29] G. May, "Packaging Education at the Georgia Tech Packaging Research Center," *1st Internat'l Academic Conf. on Packaging Research and Education*, Atlanta, GA, March, 1998.
- [30] G. May, "Understanding the Mind of the Professor," *NSBE National Convention*, Anaheim, CA, March, 1998.
- [31] G. May, "Semiconductor Process Modeling and Control with Neural Networks," *Invited Seminar*, Epitaxial Materials Manufacturing Workshop, *International Microwave Symposium*, Denver, CO, June, 1997.
- [32] G. May, "Intelligent Semiconductor Manufacturing Using AI and Neural Networks," *Invited Seminar*, Analog Devices, Inc., Wilmington, MA, May, 1997.
- [33] G. May, "Intelligent Semiconductor Manufacturing Using AI and Neural Networks," *Invited Seminar*, Texas Instruments Semiconductor Process and Device Center, Dallas, TX, January, 1997.
- [34] G. May, "Academic Careers for Minority Faculty: Myth and Reality," **Invited Seminar**, UC-Berkeley Black Graduate Engineering and Science Students Spring Seminar Series, Berkeley, CA, March, 1996.
- [35] M. Ramanachalam, T. Kim, and G. May, "Modeling and Control of Via Formation by Photosensitive Polymers in MCM-D Fabrication," *2nd International Symposium on Advanced Packaging Materials*, Atlanta, GA, March, 1996.
- [36] G. May, "Neural Networks in Semiconductor Manufacturing," **Invited Seminar**, Motorola Semiconductor Products Sector, Tempe, AZ, January, 1996.
- [37] D. Stokes, T. Kim and G. May, "Real-Time Feedback Control of Reactive Ion Etching Using Neural Networks," *Sematech Advanced Equipment Control/Advanced Process Control Workshop*, New Orleans, LA, November, 1995.
- [38] K. Mitchell and G. May, "The Virtual Cleanroom Project," *EduTech Institute Winter Symposium*, Atlanta, GA, December, 1994.
- [39] G. May, "Recent Results in the Application of Neural Networks to IC-CIM," **Invited Seminar**, University of California, Berkeley, CA, April, 1994.
- [40] "The Role of Faculty in the Student Pipeline," **Invited Seminar**, National Association of Minority Engineering Program Administrators (NAMEPA) Annual Conference, Washington, DC, March, 1994.
- [41] P. Kohl, S. Bidstrup, D. Hertling, and G. May, "Materials and Processes for High Performance and Superconducting MCMs", *ARPA Electronic Packaging and Interconnect Principal Investigator Meeting*, Marina del Rey, CA, February 14-18, 1994.
- [42] M. Baker, C. Himmel, and G. May, "Time Series Modeling of Reactive Ion Etching Using Neural Networks," *Eighth Annual SRC/DARPA CIM-IC Workshop*, Pittsburgh, PA, August, 1993.
- [43] G. May, "Modeling and Diagnosis of Reactive Ion Etching," **Invited Seminar**, Digital Equipment Corporation, Hudson, MA, April, 1993.
- [44] G. May, "Effective Utilization of Neural Networks in IC-CIM Applications," **Invited Seminar**, University of California, Berkeley, CA, April, 1993.
- [45] B. Kim and G. May, "The Effect of Network Structure and Learning Parameters on Neural Network Models of

Semiconductor Processes," *Seventh Annual Semiconductor Research Corporation SRC/DARPA IC-CIM Workshop*, Stanford, CA, August 5, 1992.

- [46] G. May, "Monitoring, Modeling and Diagnosis of Reactive Ion Etching," **Invited Seminar**, IBM Thomas J. Watson Research Center, Yorktown Heights, NY, July, 1992.
- [47] G. May, "The Efficient NSBE Leader," *NSBE Region III Leadership Retreat*, Huntsville, AL, October, 1991.
- [48] G. May and C. Spanos, "The Berkeley Computer-Aided Manufacturing System," *Industrial Liaison Program*, Berkeley, CA, March, 1991.
- [49] G. May, "Automated Diagnosis of a Plasma Etcher," *Technet*, Birmingham, AL, October, 1990.
- [50] G. May and C. Spanos, "Modeling and Diagnosis of a Plasma Etcher," *Fifth Annual Semiconductor Research Corporation SRC/DARPA IC-CIM Workshop*, Berkeley, CA, August, 1990.
- [51] G. May, "Automated Diagnosis of Integrated Circuit Fabrication Equipment," *National Society of Black Engineers National Conference*, Orlando, FL, March, 1990.
- [52] G. May, "The State of the Art in Plasma Etch: Process Modeling, Monitoring & Diagnosis," *Berkeley Computer Integrated Manufacturing Seminar*, Berkeley, CA, April, 1989.
- [53] G. May, "On-Line Diagnosis of IC Process Equipment," *Semiconductor Research Corporation Computer Integrated Manufacturing Retreat*, Berkeley, CA, January, 1989.

Keynote Addresses

- [1] "Welcome to Georgia Tech," Georgia Tech Freshman Convocation, Atlanta, GA, August, 2000.
- [2] "The Choice is Yours," Ralph Bunche Middle School Honors Banquet, Atlanta, GA, April, 1998.
- [3] "The Ph.D. and Your Responsibility," Black Graduate Students Association Spring Banquet, Atlanta, GA, May, 1997.
- [4] "A Note to the Next Generation," Southeastern Consortium for Minorities in Engineering (SECME) 7th Annual Atlanta Alliance Recognition Banquet, Atlanta, GA, April, 1996.
- [5] "Engineering: A Worthwhile Career Choice for You," Pre-College Mini Conference, *NSBE National Convention*, Nashville, TN, March, 1996.
- [6] "Engineering: A Worthwhile Career Choice for You," *NSBE Region III Fall Conference*, Atlanta, GA, November 13, 1993.
- [7] Keynote Address, North Alabama NSBE Alumni Chapter Scholarship Banquet, Huntsville, AL, March, 1993.
- [8] Keynote Address, Southeastern Consortium for Minorities in Engineering (SECME) Annual Honors and Awards Banquet, Knoxville, TN, May, 1992.
- [9] Keynote Address, Georgia Tech Society of Black Engineers High School Outreach Banquet, Atlanta, GA, November, 1991.
- [10] G. May, "The Next Generation of Engineers," Southeastern Consortium for Minorities in Engineering (SECME) Summer Institute Scholars Luncheon, Tallahassee, FL, June 26, 1991.